

SSR cavity processing plans at FNAL/ANL and IJCLab

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On behalf of all contributors to PIP-II SSR at IJCLab/FNAL/ANL/DAE

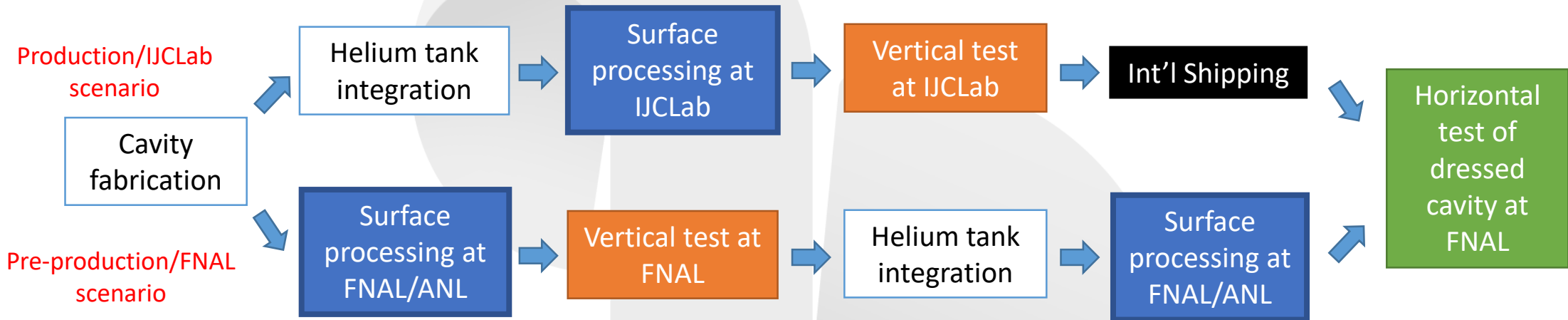


- Preliminary cavity flow chart for SSR cavity surface processing
- Description and acceptance criteria for specific steps :
 - BCP
 - H-degassing
 - HPR + drying + assembly
 - Frequency tuning
 - Low temperature baking
 - Vertical test
 - Horizontal test



Preliminary cavity flow chart for cavity surface processing

- Base-line flow chart already suggested during FDR of pre-production SSR2 cavity
- Flow charts are aligned between FNAL/ANL and IJCLab even though cavity configuration is different
 - FNAL/ANL => Bare Cavity
 - IJCLab => Jacketed Cavity
- FNAL/ANL flow chart is extended after tank integration but is necessary to fully qualify pre-production cavities.
- IJCLab flow chart is short-cutted but is production-like (no bare cavity processing as no possibilities of dunk test)

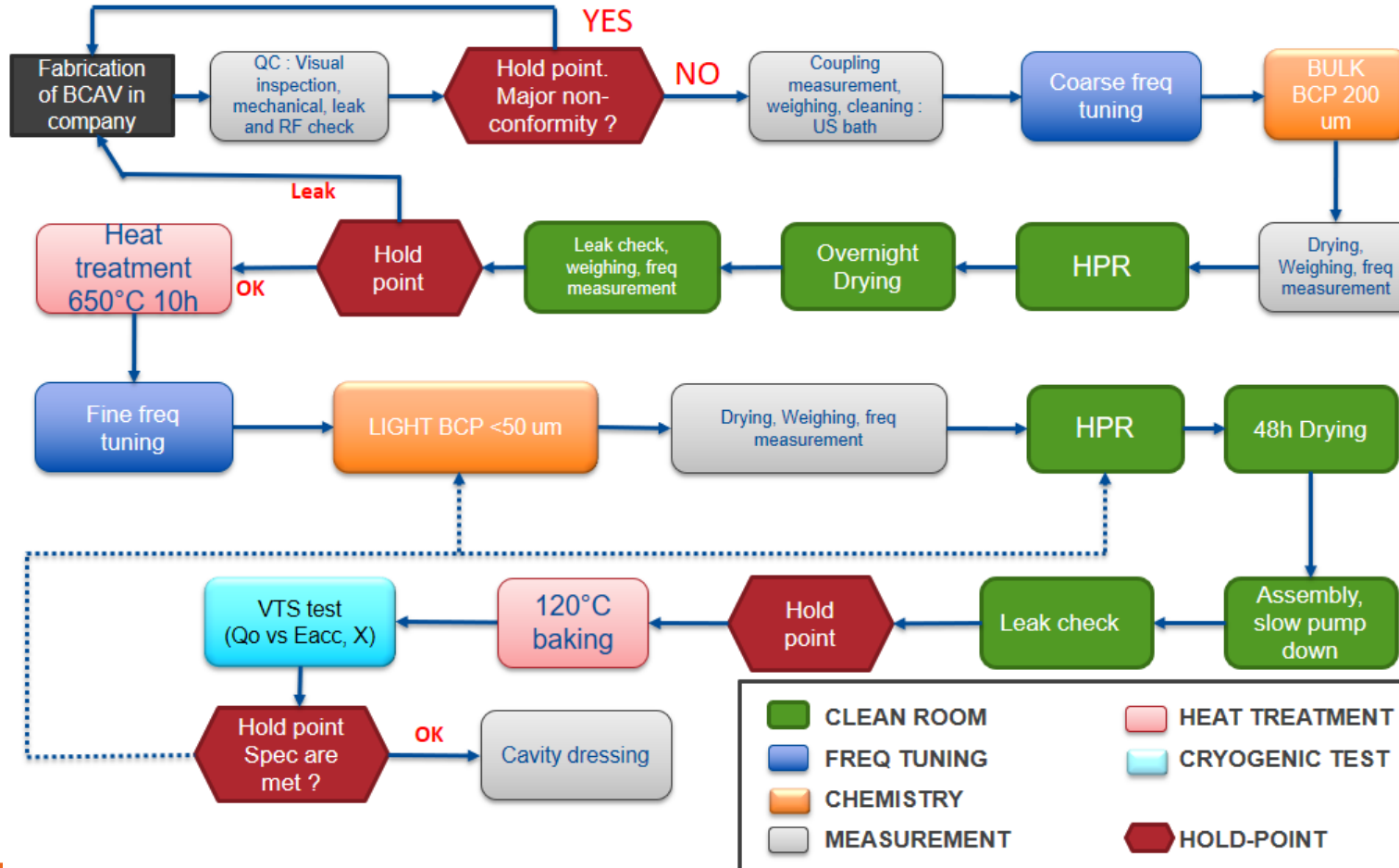




Preliminary cavity flow chart for cavity surface processing

Charge 1e Fermilab

SSR2 bare cavities processing and testing flow





Description and acceptance criteria for specific steps

- BCP treatment

- Remove damaged layer from fabrication

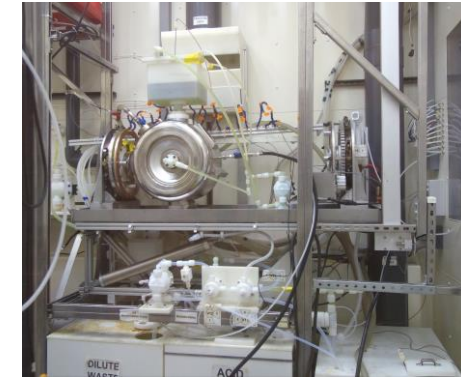
REQUIREMENTS	TECHNIQUE	ACCEPTANCE CRITERIA
Average removal	Weighing Ultrasonic probe	Average removal (bulk) : 120-180 μm Average removal (flash) : $\sim 25 \mu\text{m}$
Maximum local removal	Ultrasonic probe	$< 400 \mu\text{m}$
Minimum thickness	Ultrasonic probe	$> 3.75 \text{ mm}$
Acid bath/cavity cooling	Temperature monitoring	$< 15^\circ\text{C}$
Defect free surface	Optical inspection (endoscop)	No visible defects
No leak	Leak detection	$< 10^{-10} \text{ mbar.l.s}^{-1}$

- Paths for optimization :

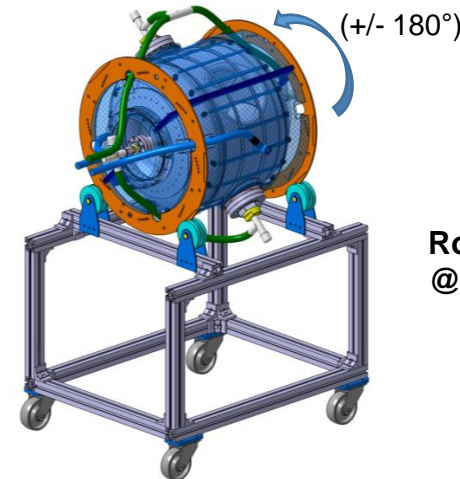
- Rotational BCP : improve homogeneity of material removal, avoid appearance of surface defects : grooves, white drips, ...



Etching lab @ IJCLab



Etching lab @ ANL



Rotational BCP for SSR2
@ IJCLab



Description and acceptance criteria for specific steps

• H-Degassing

- Degas hydrogen out from Niobium.
- Release material stress

REQUIREMENTS	TECHNIQUE	ACCEPTANCE CRITERIA
Heat above 600°C during 10h	Temperature monitoring	Temperature cycle is normal
Degas hydrogen	RGA scan	Observe degassing peak of H H Partial Pressure decreased of
Limit mechanical stress	Heating steps Heating ramp	Hold 1h at 300°C $dT/dt < 2^{\circ}\text{C}/\text{min}$
No pollution with hydro-carbons	RGA scan	HC Partial Pressure below ??
Defect free	Optical inspection (endoscop)	No visible defects
No leak (RF and helium volume)	Leak detection	$< 10^{\text{E}-10} \text{ mbar.l.s}^{-1}$

• Paths for optimization :

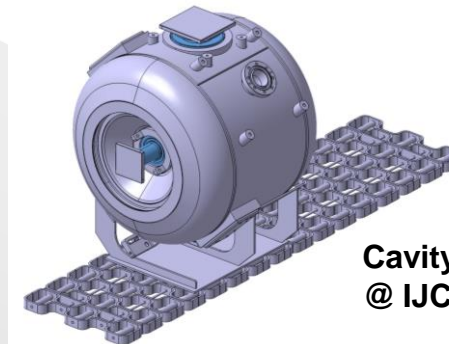
- Remove flash BCP after H-degassing
- Increase temperature to foster re-cristallization (800°C) ?



Furnace @ IJCLab



Furnace @ FNAL



Cavity support for furnace
@ IJCLab



Description and acceptance criteria for specific steps

- **HPR + drying + assembly**

- Remove any surface pollution from the surface
- Required before and after Hydrogen degassing

REQUIREMENTS	TECHNIQUE	ACCEPTANCE CRITERIA
Hit all surface with water jet	TBD	Rinsing time > ??h Nozzle translation speed < ?? mm/s
Drying of surfaces before assembly		Drying time > 48h
Maintain cavity cleanliness during assembly	Parts degreasing Particle counting on parts (N2 blowing)	Number of particle below 0.5um : ??
Maintain cavity cleanliness during pump down	Slow pump down	< 1mbar.s ⁻¹ down to 1 mbar



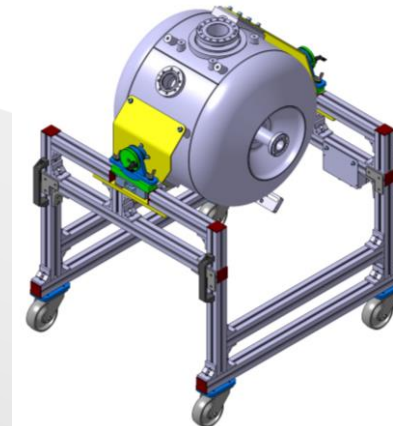
HPR unit @ IJCLab



HPR unit @ FNAL

- **Paths for optimization :**

- In-line or sampled Particle monitoring in water during HPR
- Dynamic drying (heat up cavity before/after assembly ?)



HPR cart for SSR2
@ IJCLab

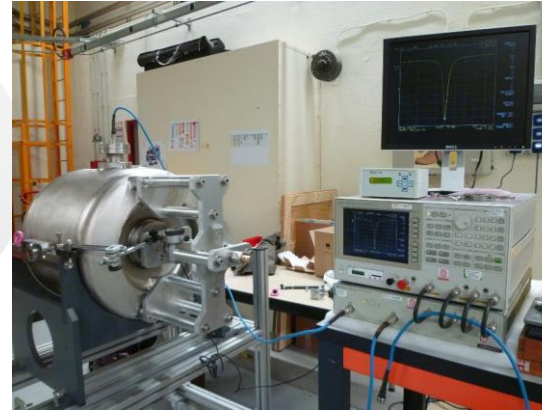


Description and acceptance criteria for specific steps

• Frequency tuning

- Reach frequency target
- Measure cavity stiffness

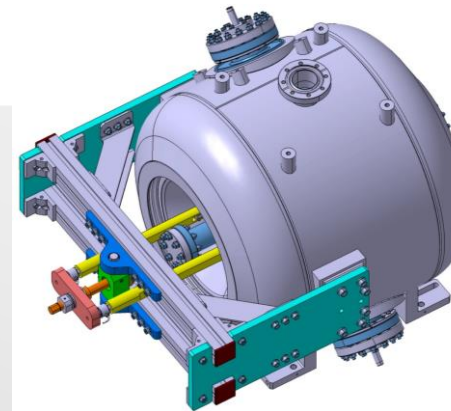
REQUIREMENTS	TECHNIQUE	ACCEPTANCE CRITERIA
Reach frequency target	VNA	Target +/- 30 kHz ??
Evaluate longitudinal stiffness	Force gauge Displacement gauge	< 16 kN/mm
Evaluate tuning sensitivity	VNA Displacement gauge	> 250 kHz/mm



**Frequency tuning of
MYRRHA @ IJCLab**



**Frequency tuning of
SSR1 @ FNAL**



**Frequency tuning of SSR2
@ IJCLab**



Description and acceptance criteria for specific steps

- **Low temperature baking**

- Reduce multipacting
- Improve Q-slope (to be demonstrated)

REQUIREMENTS	TECHNIQUE	ACCEPTANCE CRITERIA
Heat above 120°C during 48h	Temperature monitoring	Temperature cycle is normal
Reduction of H ₂ O partial pressure	RGA scan	$P_{H_2O_{final}} = P_{H_2O_{before}}/10$ (??)



LTB set-up @ IJCLab



LTB set-up @ FNAL

- Paths for optimization :
 - No LTB ? (not required if no Q-slope at operating gradient and very limited multipacting)



Description and acceptance criteria for specific steps

- **Vertical testing**

- Validation of cleaning procedure
- Validation of cavity performance

REQUIREMENTS	TECHNIQUE	ACCEPTANCE CRITERIA (jacketed)
Vacuum level before cooling down and at 2K	Vacuum gauge	$< 10^{-7}$ mbar
Achieve minimum gradient	RF measurement	13.7 MV/m
Qo at 5 MV (11.5 MV/m)	RF measurement	$> 8 \times 10^9$ (jacketed) $> 9 \times 10^9$ (bare)
Frequency at 2K at 5 MV (11.5 MV/m)	Frequency meter	325 MHz \pm 65 kHz (without tuner) 325 MHz (with tuner)
No field emission at 5 MV	X-rays detector	< 1 μ Sv/h in beam tube axis
No multipacting up to 5 MV (after RF processing)	RF measurement X-rays detector	Pick-up signal stable < 1 μ Sv/h in beam tube axis
Sensitivity to Lhe pressure (with tuner)	Frequency meter	< 25 Hz/mbar (with tuner)
Sensitivity to Lorentz forces (with tuner)	Frequency meter RF measurement	< 5 Hz/(MV/m) ² (with tuner)
Field probe level @ 5 MV	RF measurement	300 mW \pm 200 mW



Vertical cryostat @ IJCLab



Vertical cryostat @ FNAL

Fermi National Accelerator Laboratory



PIP-II SSR2 Cavity, Coupler and Tuner
Technical Requirements Specification

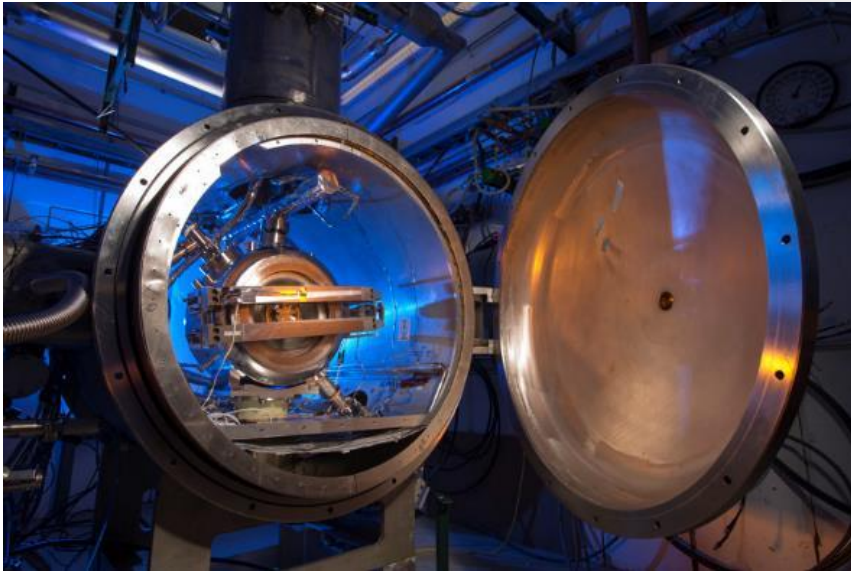
Document number: ED0009784, Rev. B



Description and acceptance criteria for specific steps

- Horizontal testing

- Validation of cavity performance with HPC and Tuner
- Validation of HPC assembly procedure



Horizontal cryostat @ FNAL

REQUIREMENTS	TECHNIQUE	ACCEPTANCE CRITERIA (jacketed)
Vacuum level before cooling down and at 2K	Vacuum gauge	$< 10^{-7}$ mbar
Achieve minimum gradient	RF measurement	13.7 MV/m
Qo at 5 MV (11.5 MV/m)	RF measurement	$> 8 \times 10^9$ (jacketed)
Frequency at 2K at 5 MV (11.5 MV/m)	Frequency meter	325 MHz (with tuner)
No field emission at 5 MV	X-rays detector	< 1 μ Sv/h in beam tube axis
No multipacting up to 5 MV (after RF processing)	RF measurement X-rays detector	Pick-up signal stable < 1 μ Sv/h in beam tube axis
Sensitivity to LHe pressure (with tuner)	Frequency meter Pressure gauge	< 25 Hz/mbar
Sensitivity to Lorentz forces (with tuner)	Frequency meter RF measurement	< 5 Hz/(MV/m) ²
Field probe level @ 5 MV	RF measurement	300 mW +/- 200 mW
Operating cavity Q-loaded	VNA	5.05×10^6 +/- 25%
Slow tuner frequency range	Frequency meter	> 130 kHz
Fast tuner frequency range	Frequency meter	> 700 Hz
Hysteresis	Frequency meter	$< ??$ Hz



Conclusion

- Preliminary cavity flow chart has been developped jointly for SSR2 FDR
 - Same flow chart should be applied by all involved partners.
 - Some differences can exist in procedures because of cavity configuration (bare/jacketed) and facilities.
- Acceptance criteria for each step should be jointly defined
 - A preliminary list is suggested and should be finalized before delivery of pre-production cavities.
 - The flow chart and acceptance criteria have to be updated/adapted during pre-production phase and finalized to be validated at FDR of production cavities.
 - Some paths of optimization have been identified and will be investigated on pre-production cavities.



BACK-UP SLIDES



Processing capabilities at IJCLab : SUPRATECH Platform



Vacuum furnace



ISO 4 clean room

Cryogenic test hall for cryomodules



Assembly hall

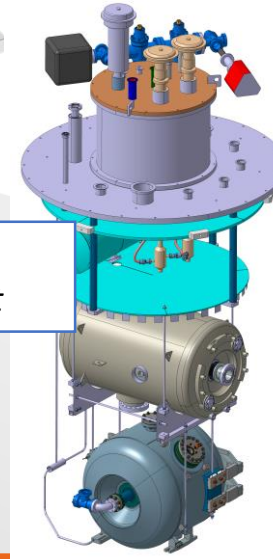


Chemical etching lab (BCP only)



Helium liquefier

Vertical cryostat



+ Material science lab



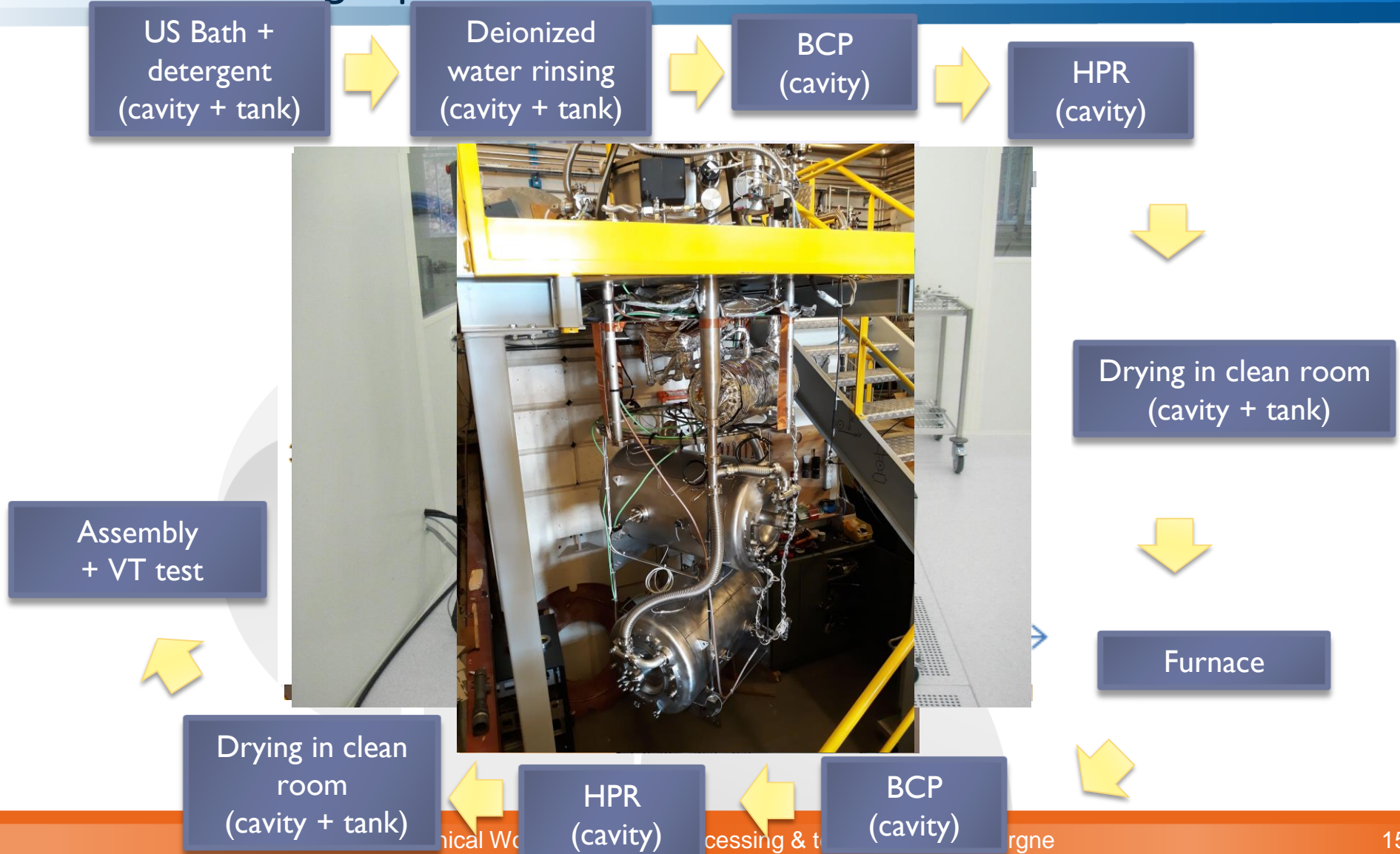
- GXR
- SIMS
- Confocal microscope
- SEM (EDS, EBSD)
- SEY measurement

+ Other

- RRR measurement (Supratech)
- Conductivity (Supratech)
- TEM (Jannus Platform)



Processing capabilities at IJCLab : SUPRATECH Platform





Current R&D on surface processing : MYRRHA Project

- No flash BCP after heat treatment

Bulk BCP
150-200 μm

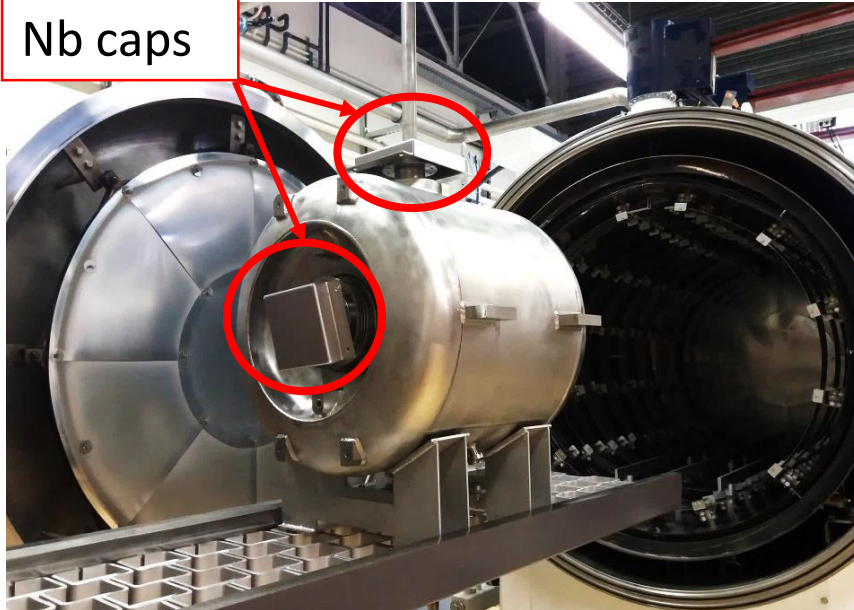
HPR

H-degassing
650°C 10h

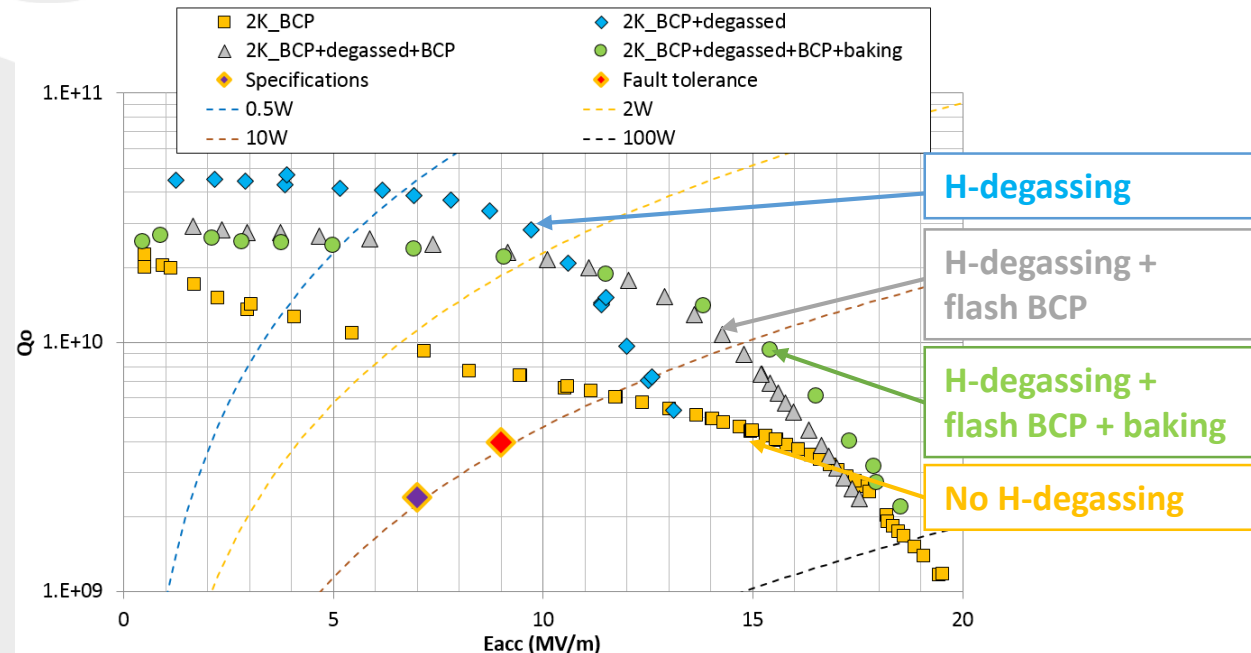
~~Flash BCP
20 μm~~

HPR

Nb caps



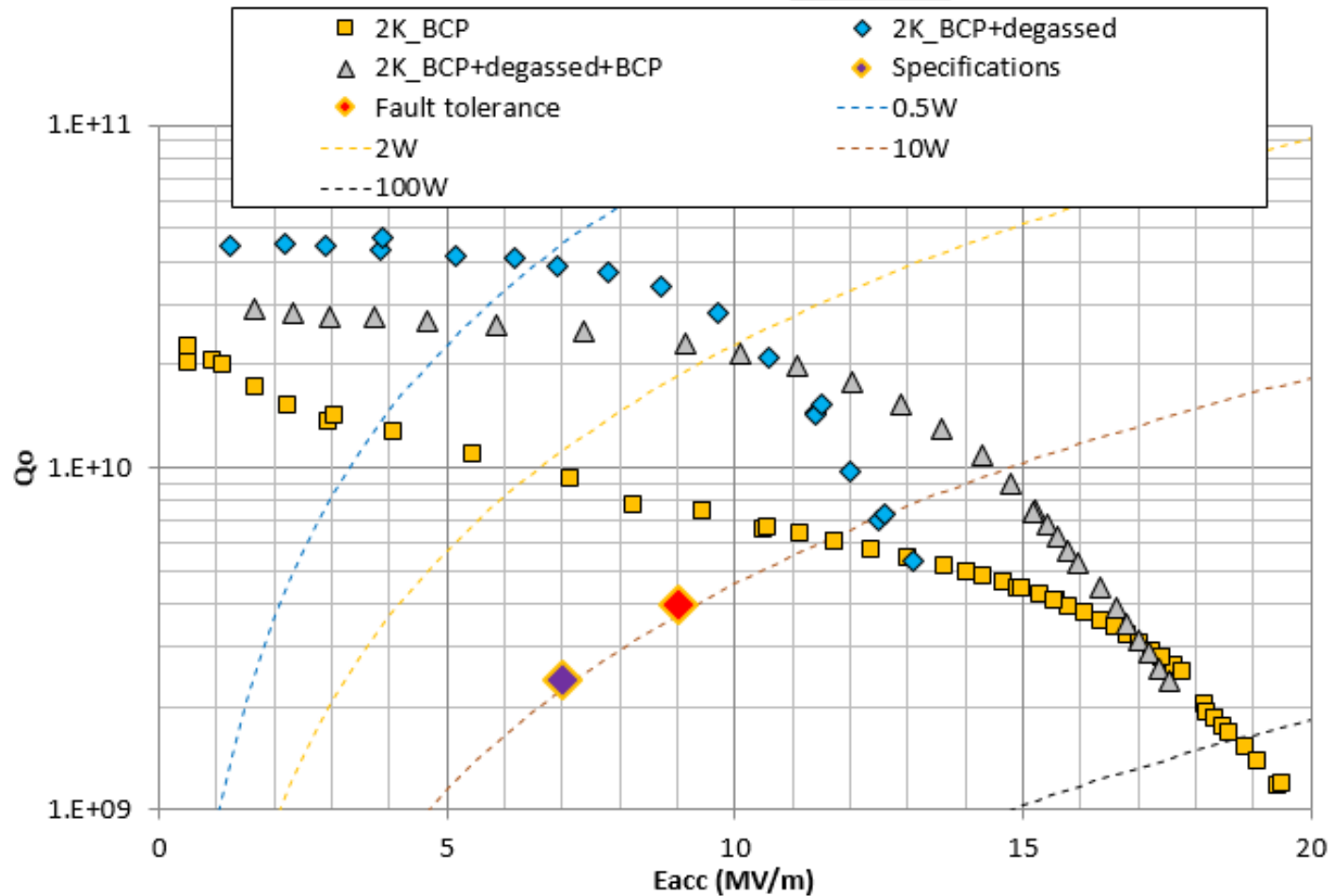
MYRRHA Simple Spoke Cavity





Current R&D on surface processing : MYRRHA Project

- No flash BCP after heat treatment

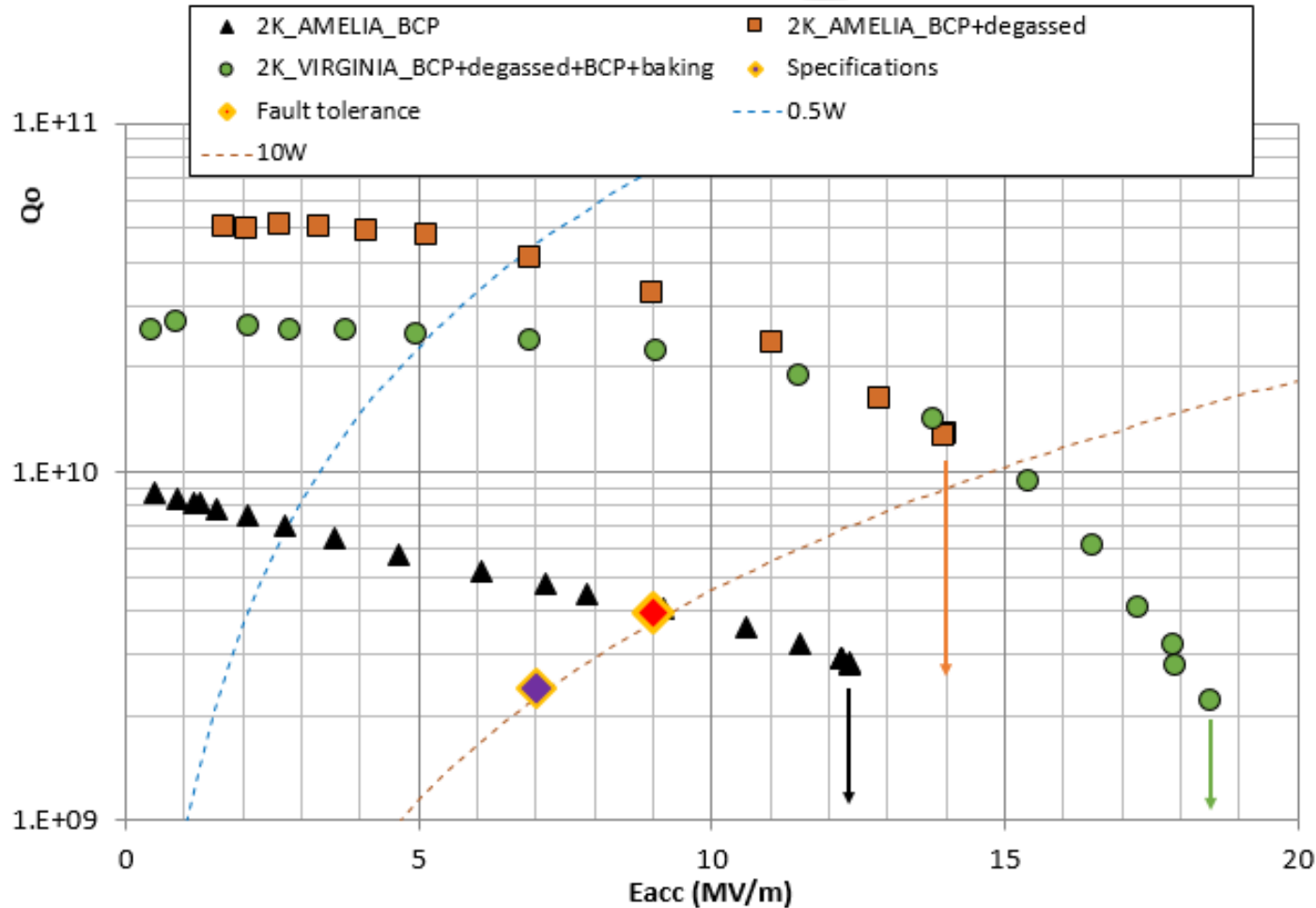


With Titanium
tank + Stainless
steel flanges





- No flash BCP after heat treatment

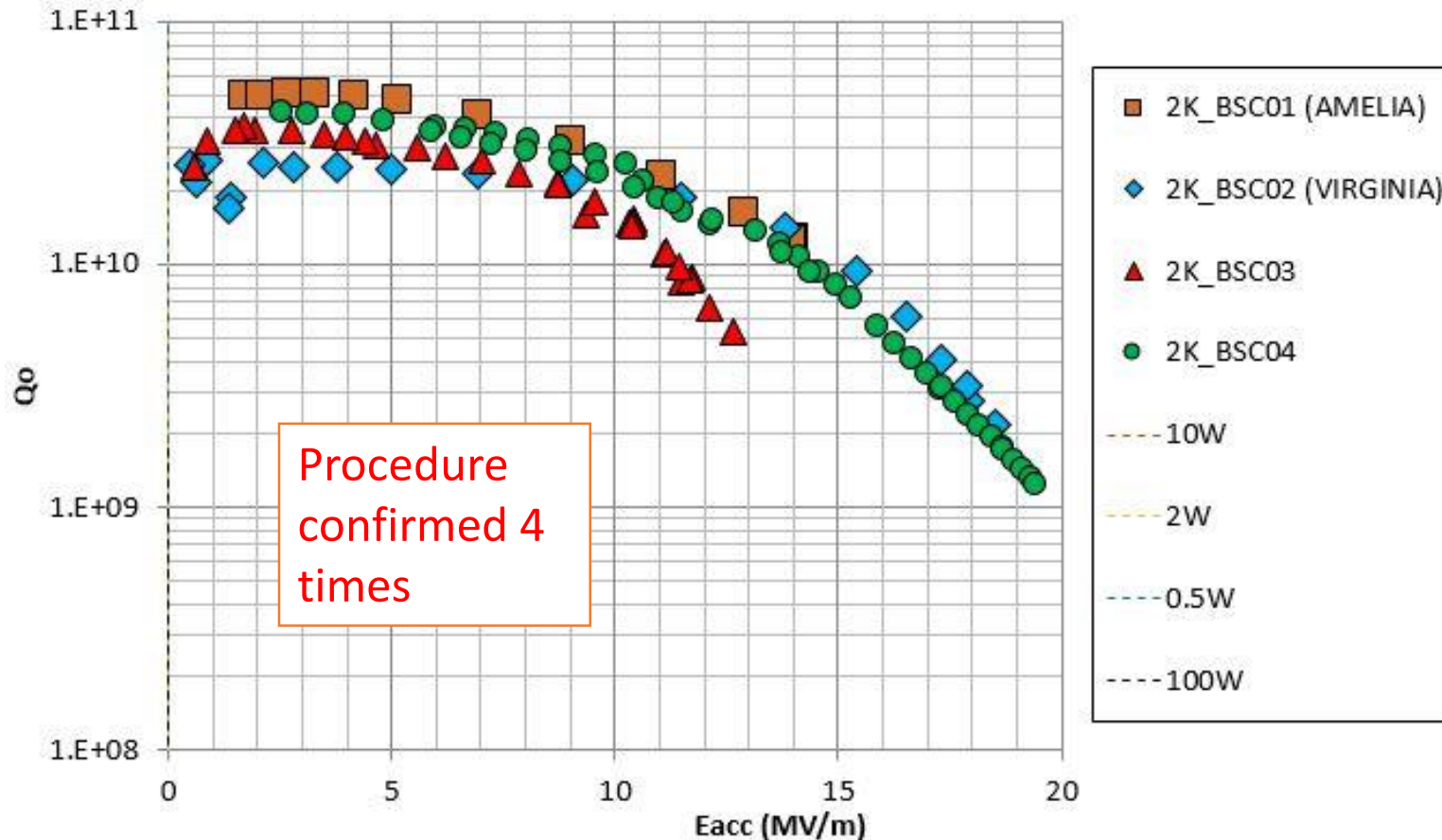


With Titanium
tank + Stainless
steel flanges





- No flash BCP after heat treatment (except blue diamond)



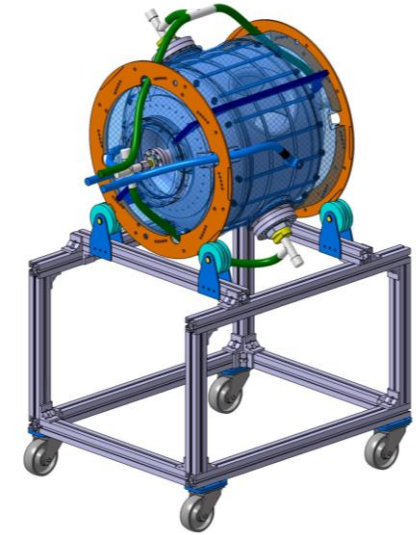
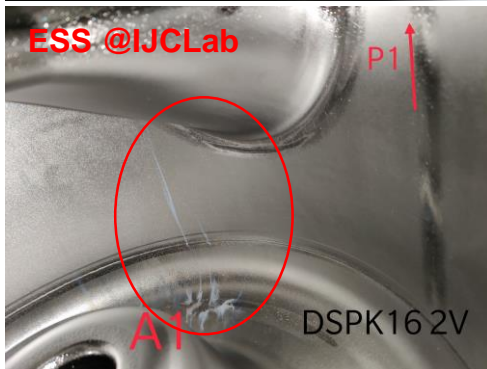
- Better Q_0 at low field ($\sim 4^{E10}$)
- Simplification of surface processing (less step => less risks)
- Need to confirm same Q_0 after frequency tuning (to be tested beginning 2021)



Upgrades for PIP-II : SSR2 prototype cavity processing

1. Improvement of BCP procedure

- How to have a better homogeneity of material removal ?
- How to avoid surface traces and white marks (coming from bubbles resting)



- Semi-rotational BCP bench (+/- 180°) at ~ 1 rpm
- Allow mixing of BCP mixture during the full process
- Avoid creation of bubbles
- Allow homogeneous water rinsing after acid draining



Upgrades for PIP-II : SSR2 prototype cavity processing

1. Heat treatment

- Validation of MYRRHA procedure: No Flash BCP after Hydrogen degassing (650°C during 10h)
- Standard baking 120°C 48h is not recommended : no benefit on Q_0 at operational gradient.
- Short baking 120°C 3h is recommended to reduce multipacting if processing is complicated.

